

FORM PTO-1449

U.S. DEPARTMENT OF COMMERCE  
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.  
MICRON.098CDV1APPLICATION NO.  
10/614,489INFORMATION DISCLOSURE STATEMENT  
BY APPLICANTAPPLICANT  
Basceri et al.FILING DATE  
July 3, 2003GROUP  
2818

USE SEVERAL SHEETS IF NECESSARY)

## U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE (IF APPROPRIATE)

## FOREIGN PATENT DOCUMENTS

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION	
							YES	NO
DV	1	WO 95/25340	09/21/95	EP				

EXAMINER INITIAL	OTHER DOCUMENTS (INCLUDING AUTHOR, TITLE, DATE, PERTINENT PAGES, ETC.)	
DV	2	Joo, "Fabrication and Characterization of MOCVD (Ba, Sr)TiO <sub>3</sub> Thin Films for High Density Capacitors", Proceeding of 1997 5th International Conference on VLSI and CAD, The Secretariat of ICVC '97, 1997.

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050704

EXAMINER	<i>Shuland</i>	DATE CONSIDERED	10/15/04
<p>*EXAMINER: INITIAL IF CITATION CONSIDERED, WHETHER OR NOT CITATION IS IN CONFORMANCE WITH MPEP 609; DRAW LINE THROUGH CITATION IF NOT IN CONFORMANCE AND NOT CONSIDERED, INCLUDE COPY OF THIS FORM WITH NEXT COMMUNICATION TO APPLICANT.</p>			